

IN THE UNITED STATES OF PATENT AND TRADEMARK OFFICE

Applicant : Thomas Jung
Appl. No. : 09/743,545
Filed : March 1, 2001
Title : DEVICE AND METHOD FOR THE VACUUM PLASMA
PROCESSING OF OBJECTS
Class :
Int'l. Class : 1741
Docket No. : 65,243-001



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AMENDMENT

Honorable Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

In response to the Office Action of October 4, 2002, please amend the above-identified application as follows:

IN THE CLAIMS

Please cancel claims 1-19.

Please add the following new claims:

20. (New) A device for the plasma treatment of objects in a vacuum comprising;
- a box-shaped structure of an electrically conductive material defining a vacuum chamber to which a vacuum may be applied,
- a support for supporting and electrically insulating the objects from the surrounding box-shaped structure,
- said box-shaped structure including at least one opening that can be opened for ingress and egress of objects and closed,
- said box-shaped structure including a working gas inlet for supplying a working gas and a working gas outlet for discharging the working gas,